

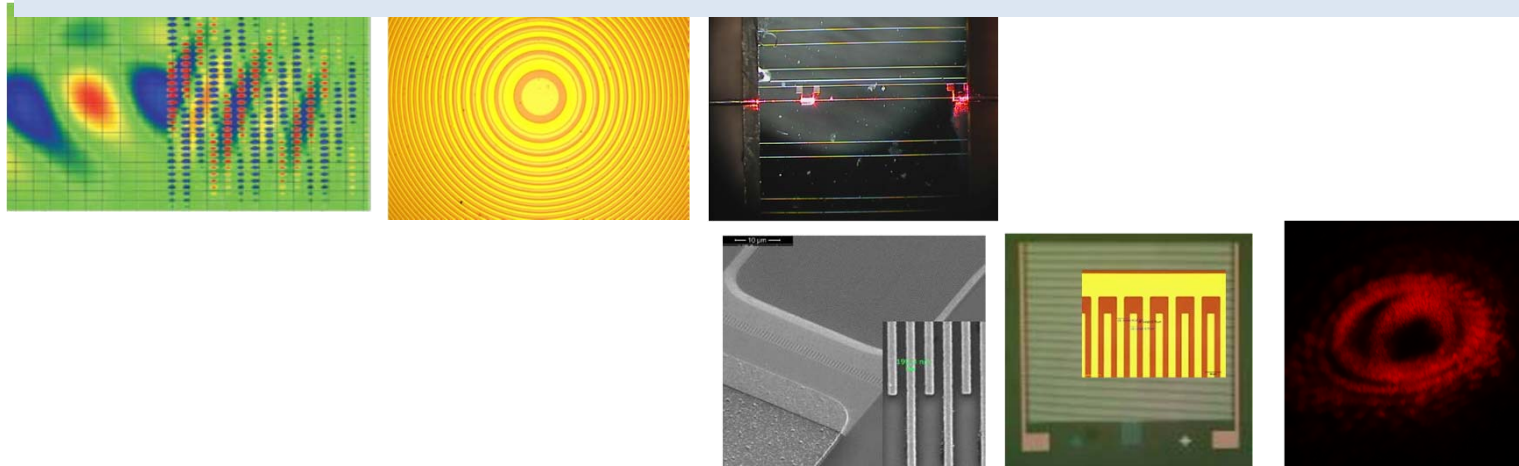


„Parteneriat în exploatarea Tehnologiilor Generice Esențiale (TGE) utilizând o
PLATformă de interacțiune cu întreprinderile competitive” (TGE-PLAT)”

"Rezultate obținute în cadrul proiectelor IMT pentru direcția "Fotonică"

Laboratorul de Micro- si Nanofotonică

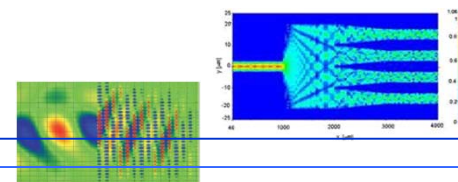
Sef Laborator: Dr. Dana Cristea



Domenii de cercetare

Modelare, simulare, CAD structuri micro si nano-fotonice

- Dispozitive si circuite integrate optoelectronice
- Circuite fotonice integrate
- Componente de microoptica si elemente optice difractive
- OMEMS



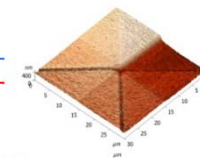
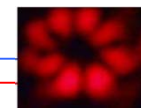
Noi materiale pentru micro-si nano-fotonica (nanocompozite hibride cu proprietati optice controlate, oxizi semiconductori transparenti, grafena, puncte cuantice), **noi procese si dezvoltare de dispozitive**

Materiale

Procese

Dispozitive

Componente micro-nano-fotonice: componente microoptice, DOE, structuri plasmonice, componente si circuite de optica integrata



Directii noi

- optoelectronica organica (incluzand si dispozitive pe baza de nanocompozite grafena-polimer)
- electronica transparenta
- metasuprafete plamonice

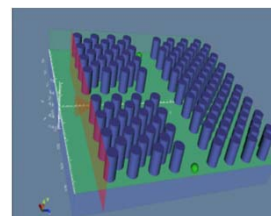
Caracterizari optice si electrice
pentru materiale si dispozitive



Facilitati

Modelare si simulare:

- **Opti FDTD 12.2.1** – proiectare, modelare, simulare, CAD a componentelor fotonice pasive si neliniare prin metoda FDTD (Finite-Difference Time-Domain)
- **OptiBPM 11.0** - proiectare, modelare, simulare, CAD a ghidurilor optice si a circuitelor fotonice integrate complexe prin metoda BPM (beam propagation method).
- **OptiGrating , LaserMod**
- **3Lit** – design pentru elemente micro-optice 3D.
- **Zemax** –design optic.



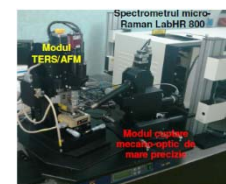
Tehnologie

- glove box pentru prepararea si depunerea nanocompozitelor si straturilor organice



Caracterizare:

- **Spectrofotometre** pentru domeniul UV-VIS-NIR si IR;
- **Elipsometru spectroscopic**
- **Sistem complex** rezultat prin cuplarea **modulului TERS/AFM** la **spectrometrul micro-Raman – LabHR 800** pentru analiza nanostructurilor carbonice si oxidice (nanotuburi, nano/micro fire, grafene, nanocompozite).
- **Alpha300 S System** –microscopie de baleiaj in camp apropiat (SNOM), microscopie confocala , microscopie de forta atomica, spectrometrie Raman
- **Tensiometru Optic Theta (KSW Instruments)**
- **Montaj experimental** pentru caracterizarea optoelectronica a dispozitivelor in UV-Vis-NIR





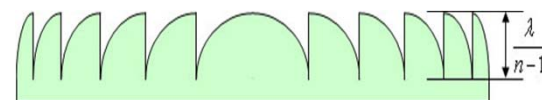
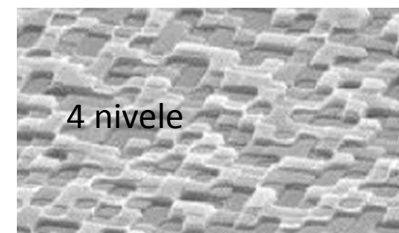
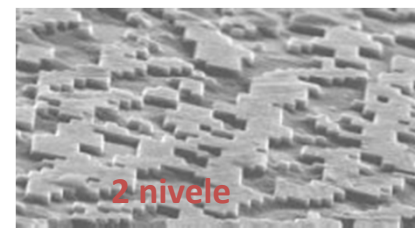
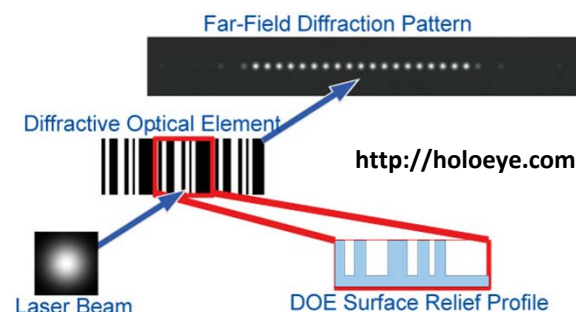
Rezultate (selectie)

- *Componete micro/nano-optice difractive*
- *Fotodetectoare*

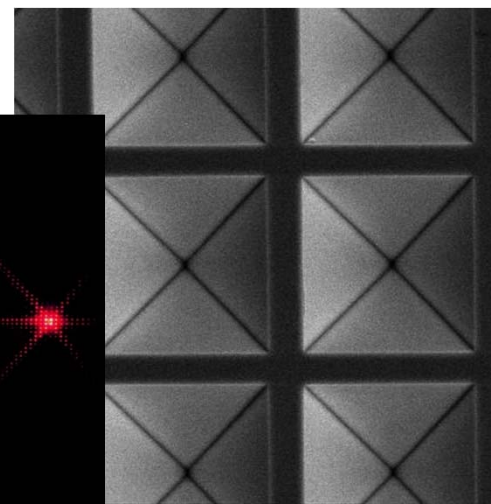
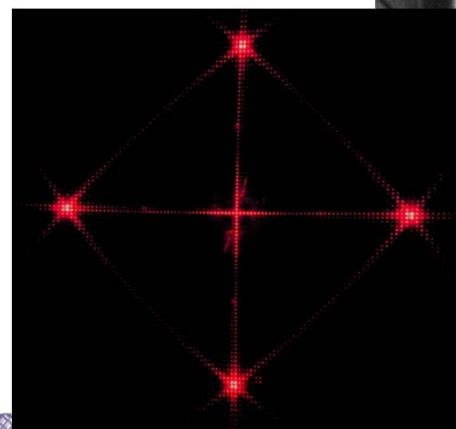
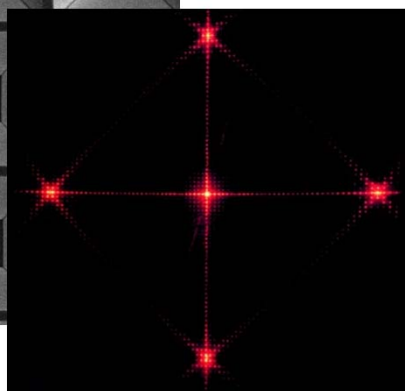
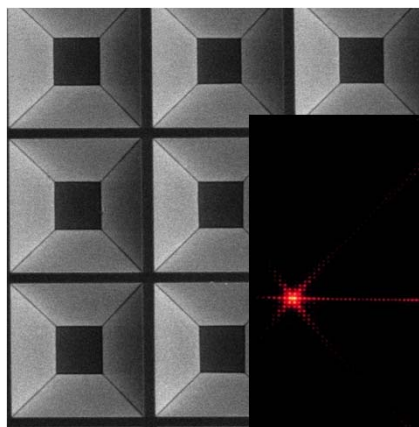
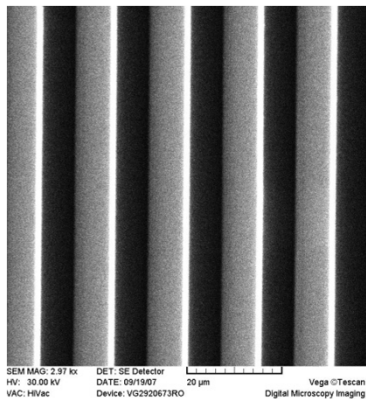
Micro-optica difractiva

Elementele optice difractive (DOE) sunt suprafețe cu structuri micro/nano-optice complexe cu ajutorul cărora se manipulează radiația laser incidentă în scopul implementării funcției optice dorite utilizând fenomenul de difracție.

- Suprafața de difracție a unui DOE constă dintr-o rețea de elemente optice micro sau nanostructurate care și prezintă o variație locală 2D a perioadei și o variație 3D a reliefului.
- Variația reliefului – în trepte (structuri binare sau multinivel) sau continuă
- DOE permit practic obținerea oricărei distribuții de intensitate a fasciculului emergent
- **Aplicații:** componente pentru comunicații optice (elemente de cuplaj, splitere, beam shaping, wave front generators, etc.), procesarea materialelor cu laserul, spectroscopie, senzori, elemente de securitate, sisteme de iluminat.

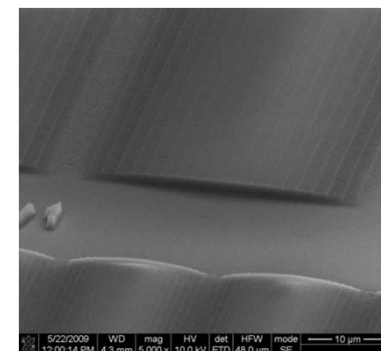
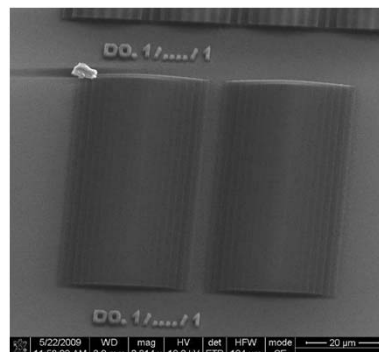
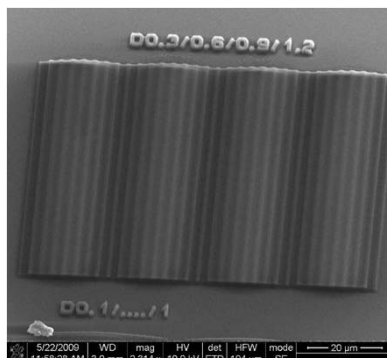
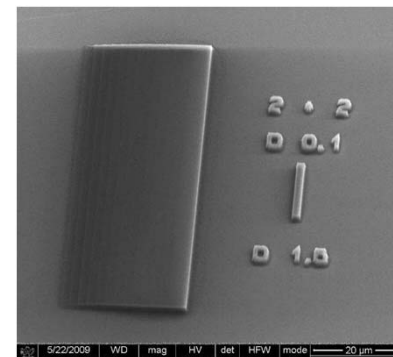
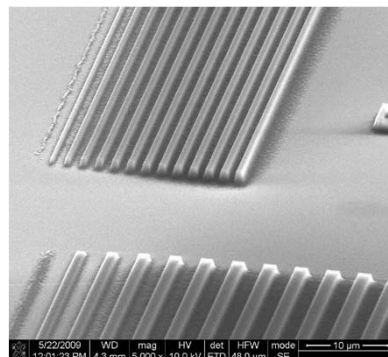
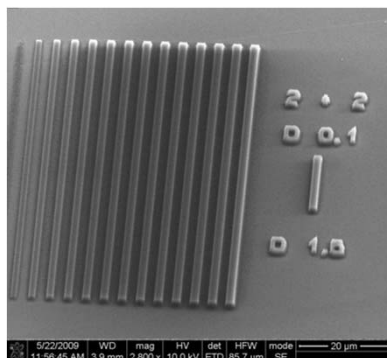


Micro-optica difractivă



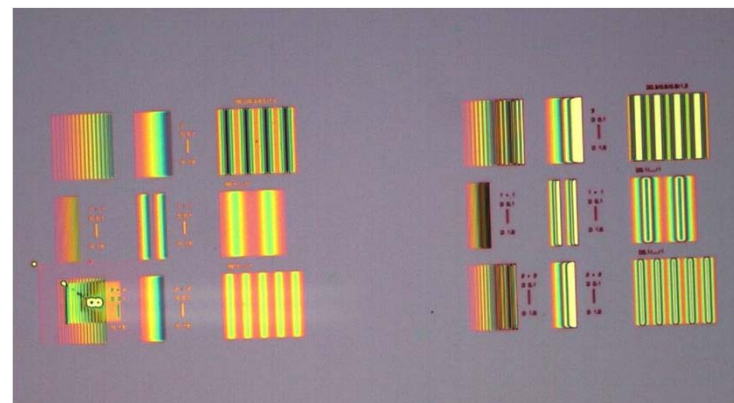
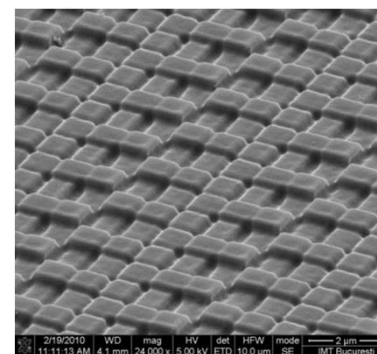
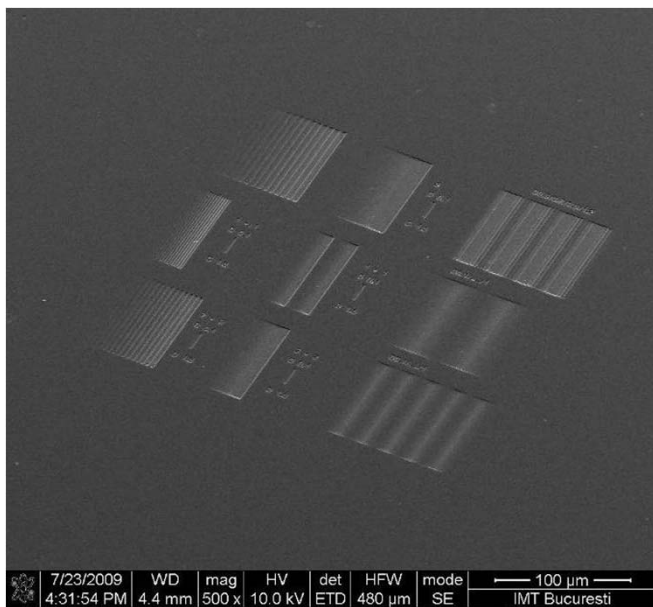
Micro-optica difractiva- Tehnologii

- Litografie 3D in rezisti cu contrast redus - **SU 8**



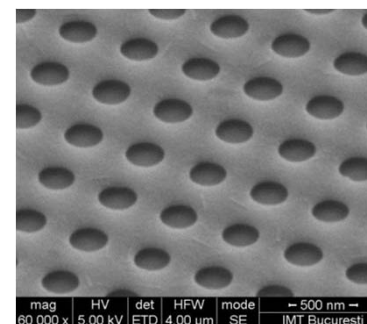
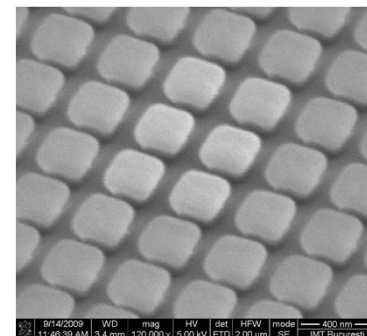
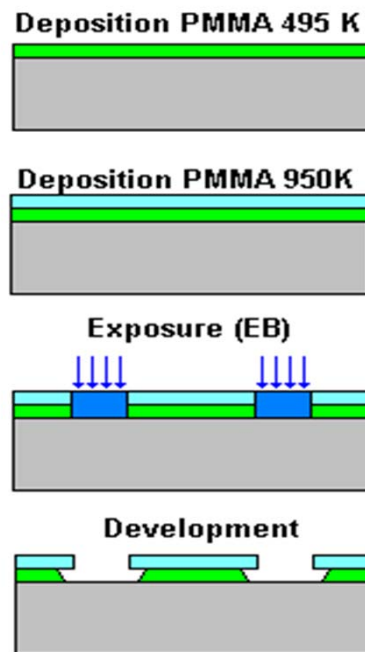
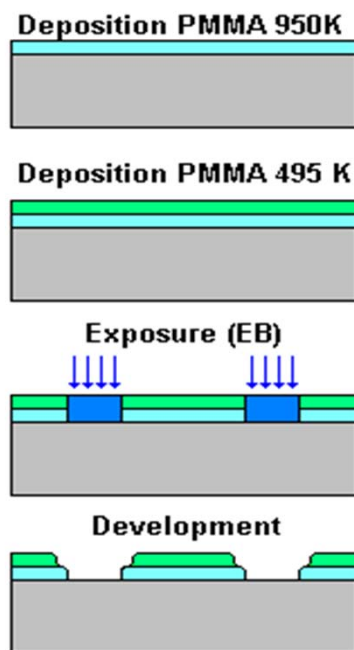
Micro-optica difractiva - Tehnologii

- Litografie 3D in rezisti cu contrast redus - **PMMA**



Micro-optica difractiva- Tehnologii

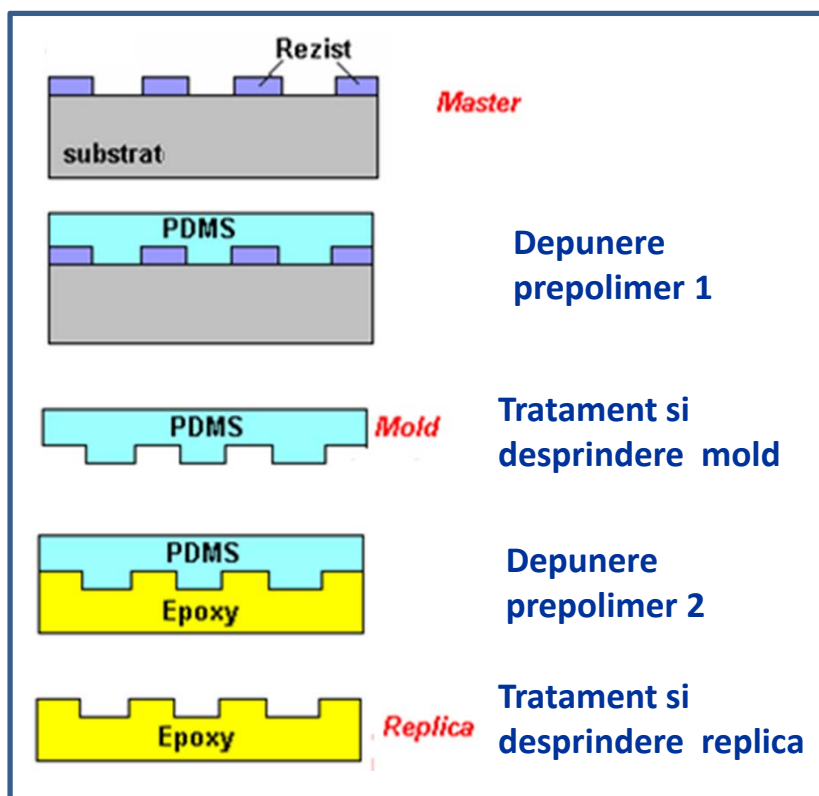
- Litografie 3D in straturi duble de rezisti



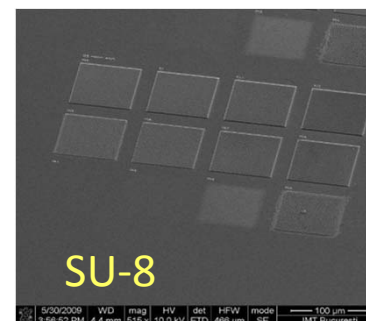
2 rezisti cu rate de dezvoltare diferite

Micro-optica difractiva- Tehnologii

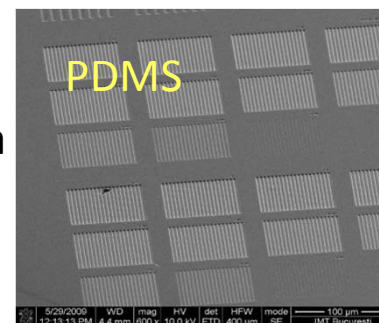
- Replicare a unor mastere cu profil 2D/3D



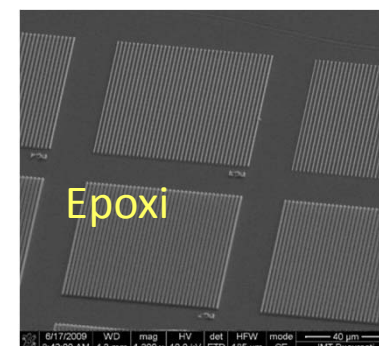
original



copie negativa



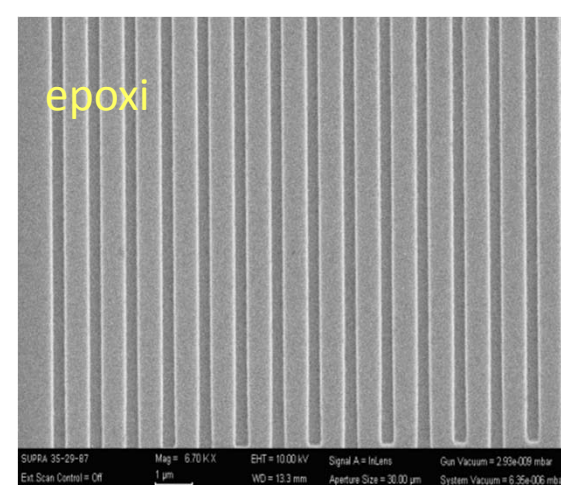
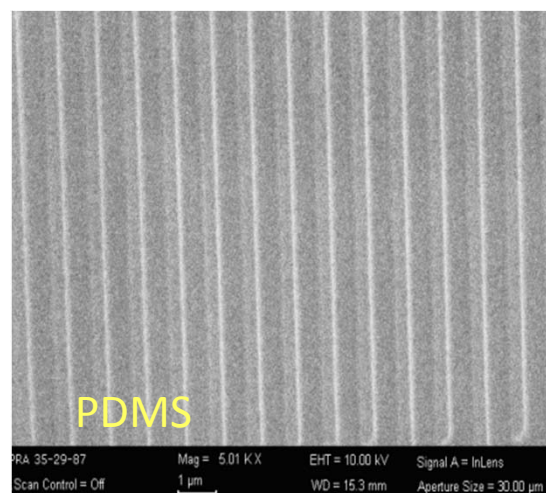
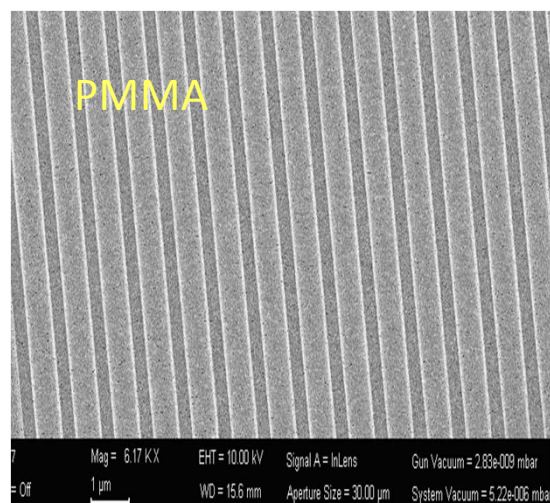
copie pozitiva



Micro-optica difractiva- Tehnologii

- Replicare a unor mastere cu profil 2D/3D

Retele de difracție- lina de 200 nm replicate in rasina epoxidica



Original



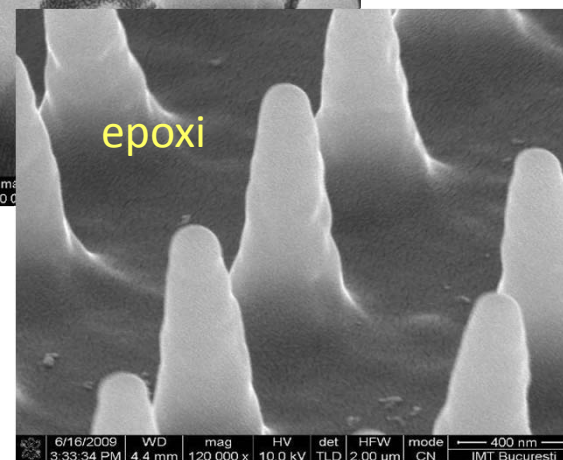
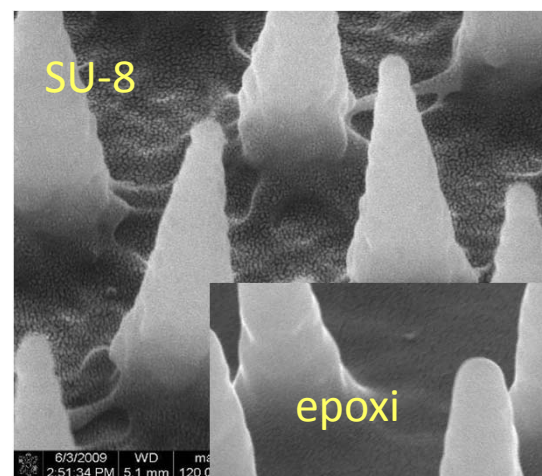
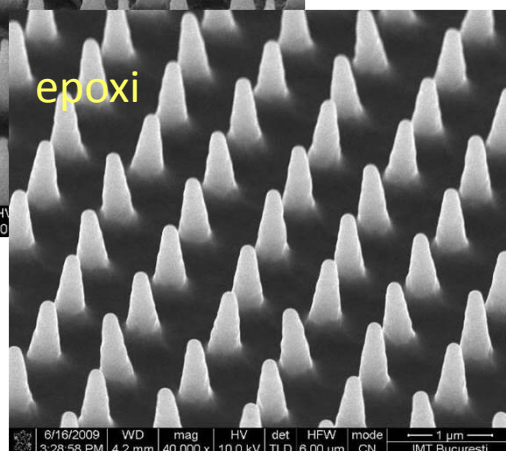
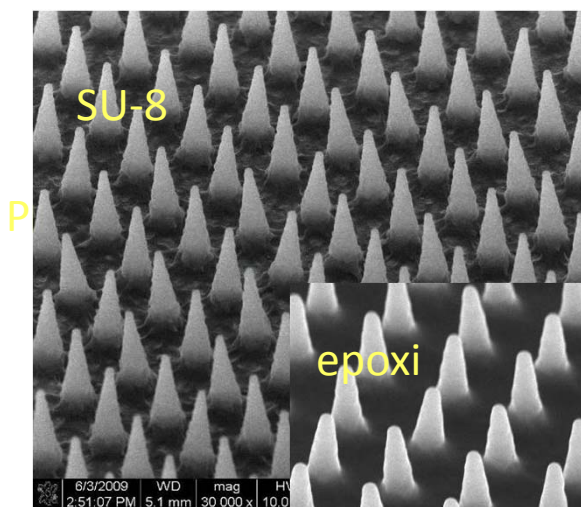
Copie negativa



Copie pozitiva

Micro-optica difractiva- Tehnologii

- Replicare a unor mastere cu profil 2D/3D

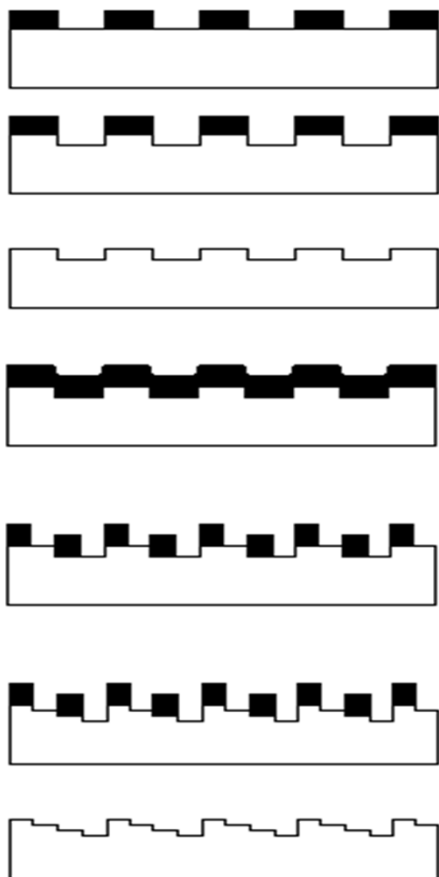


Replica in rasina epoxi resin a unor originale realizate in SU-8

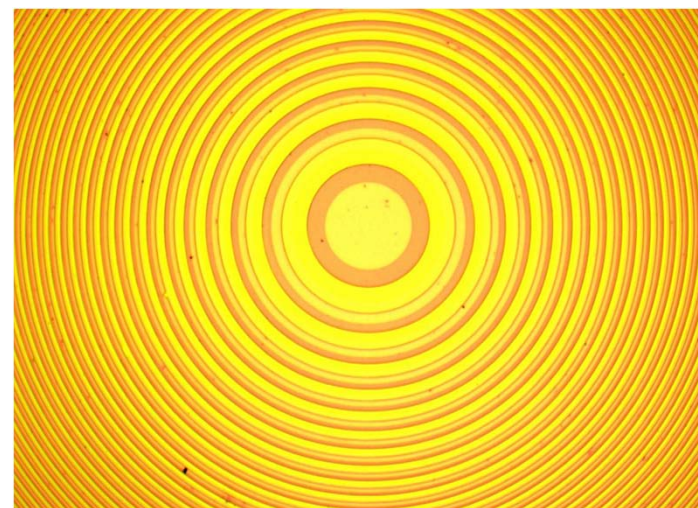
(s-a utilizat o matrita de PDMS- copia negativa)

Micro-optica difractiva- Tehnologii

- Structurii multinivel obtinute prin etape succesive de litografie si corodare



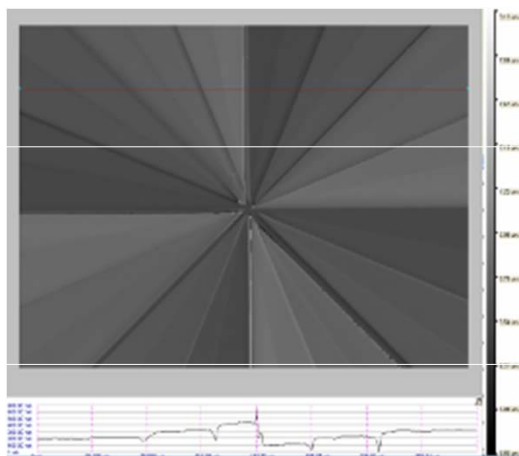
*Corodarea controlata cu
precizie de ordinul nm*



Lentila Fresnel cu 4 nivele

Micro-optica difractiva-Tehnologii

- Structurii multinivel obtinute prin etape succesive de litografie si corodare



Imaginea de interferometrie in lumina alba a unui element optic difractiv cu 8 nivele (3 masti) care genereaza un vortex optic cu ordinul $m=4$.



vortex optic de ordinul $m=4$.



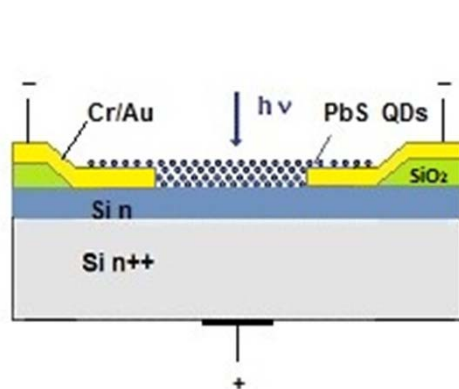
interferenta a doua vortexuri cu $m=4$ si $m=-4$.

Comunicatii optice securizate de mare capacitate prin spatiul liber, bazate pe holograme generate pe computer –Proiect PN-II-PT-PCCA 2011-2015

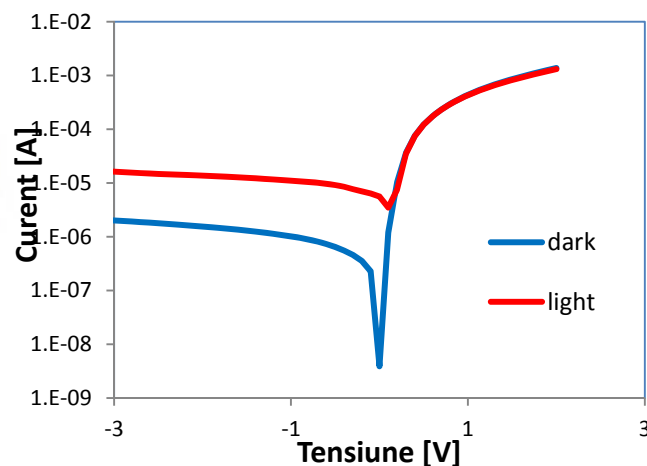
Fotodetectoare

Fotodetectoare cu raspuns imbunatatit in IR

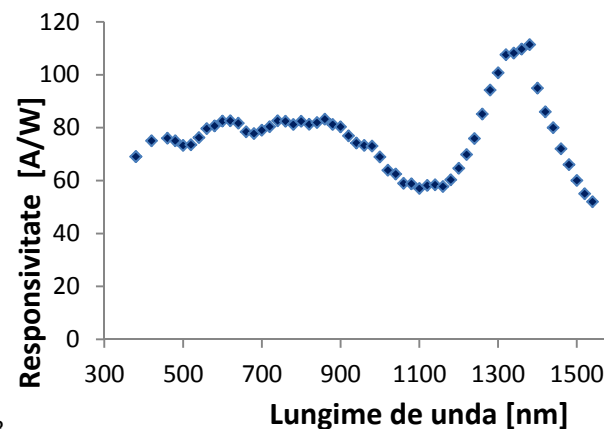
Fotodetector hibrid PbS/Si-sețiune realizate prin depunerea de straturi subtiri de puncte cuantice de PbS (PbS QDs) peste structuri Schottky Au/Si



Sețiune prin structura
si modul de polarizare



Caracteristicile I-V la intuneric
si iluminare;



Responsivitatea spectrala
($V = 1V$, $P_{opt} \sim 25 \text{ nW}$)

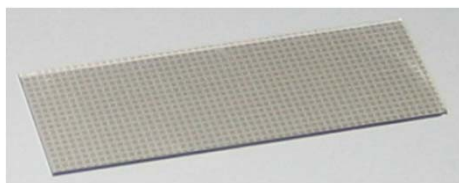
*Responsivitati in domeniul 60-100 A/W
pt. $\lambda = 350...1550 \text{ nm}$*

*Fotodetectoare pe straturi subtiri- noi concepte si
studii privind utilizarea in aplicatii aerospatiale
Proiect STAR*

Fotodetectoare

Senzori pentru radiatia UV cu factor de rejectie mare a radiatiei vizibile pe baza de straturi subtiri oxidice nanostructurate

Structurile de detectie pentru radiatia UV cu heterojunctiune transparenta s-au realizat pe substrat transparente (sticla , cuarț, substrat flexibil de PET) utilizand straturi subtiri de semiconductoare oxidice de banda larga ($> 3\text{eV}$) de tip n si p: p-NiO, n-ZnO, n-ITO, p-CuO.



structura cu heterojunctiune transparenta NiO(p)/ITO(n)

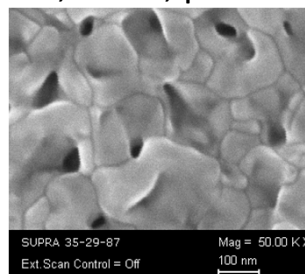
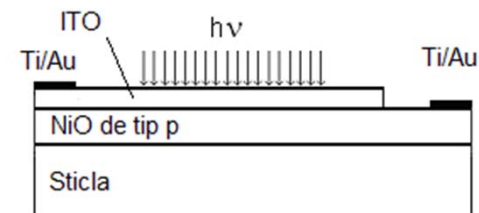
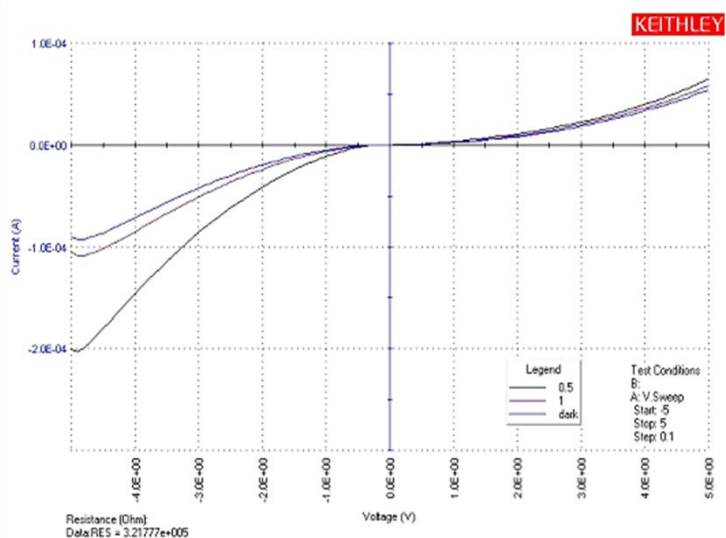


image SEM a stratului de NiO nanostructurat



reprezentare schematica a sectiunii prin structura



$$\lambda < 350 \text{ nm} - I \sim 300 \mu\text{A}$$

$$\lambda > 400 \text{ nm} - I \sim I_{\text{dark}}$$

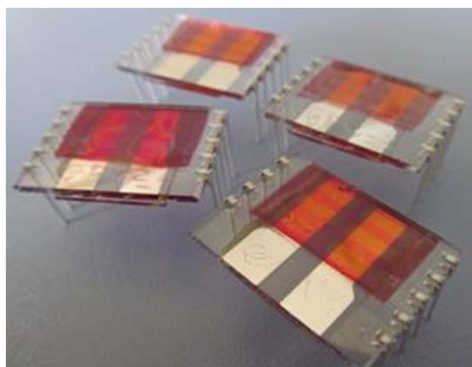
→ absorbtia radiatiei UV are loc in stratul de NiO si colectarea purtatorilor in jonctiunea transparenta

Fotodetectoare

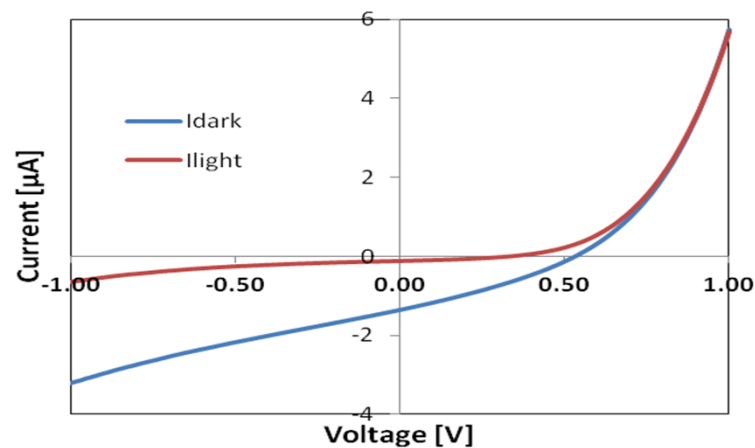
Dispozitive pe baza de nanoparticule de ZnO

Au fost obtinute componente si dispozitive experimentale de tip heterojonctiuni de volum (BHJ) sensibile la iluminare atat in vizibil cat si in UV.

Structurile experimentale obtinute de tip: ITO/ZnO/P3HT:PC61BM/PEDOT:PSS/Ag si ITO/ZnO/P3HT:PC61BM/MoO₃/Ag



Imagini ale dispozitivelor realizate

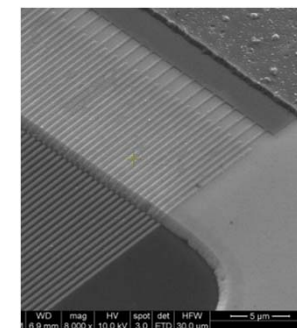
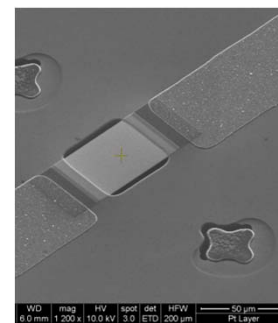


Caracteristicile I-V pentru un dispozitiv fotovoltaic de tip ITO/ZnO/P3HT:PC61BM/MoO₃/Ag cu strat de ZnO de 40 nm grosime si arie de 4,5 mm²

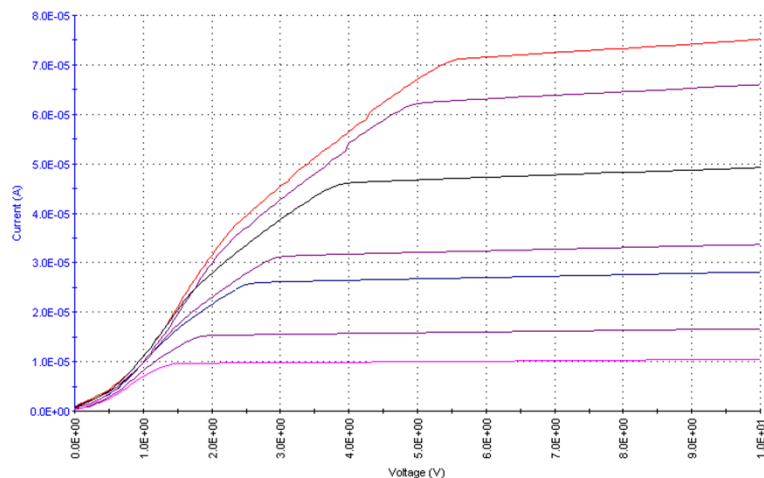
Fotodetectoare

Fotodetectoare rapide si eficiente de tip MSM cu electrozi transparenti submicronici pe straturi subtiri de materiale semiconductor

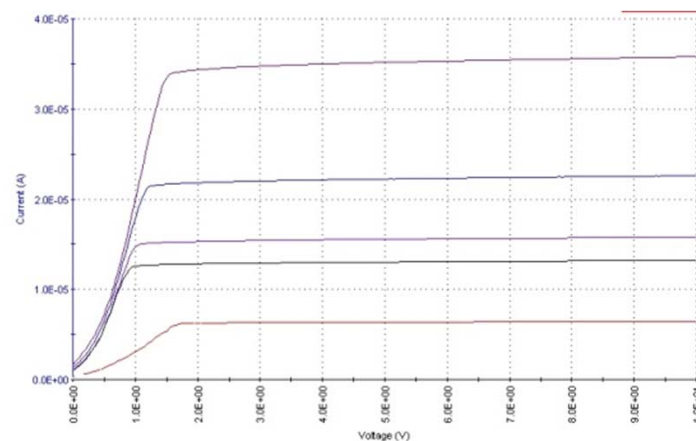
fotodetectoare de tip MSM cu electrozi interdigitati si transparenti de 150 nm si 300 nm latime din straturi oxidice transparente si conductive de tip n - ITO, ZnO pe substraturi ultrasubtiri de siliciu (~ 2 μ m plachete SOI).



Caracteristicile I-V diverse nivele de iluminare in UV (365 nm)



MSM cu electrozi de 150 nm latime



MSM cu electrozi de 300 nm latime



Mulumesc pentru atentie